

NOTES:

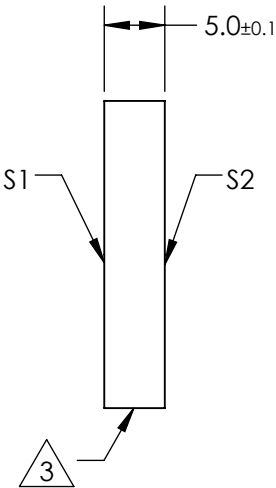
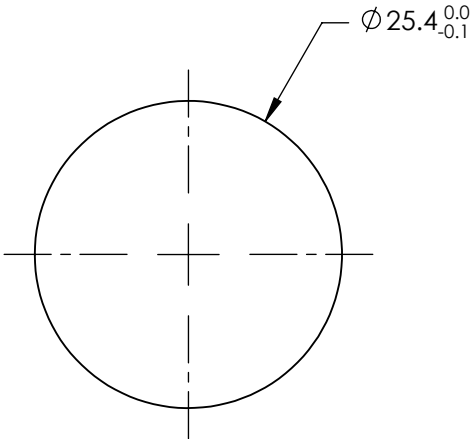
1. SUBSTRATE MATERIAL:
Fused Silica
2. COATING (APPLY ACROSS CLEAR APERTURE)

S1: Dielectric
REFLECTIVITY (Rs%, Rp%): >99.8
REFLECTIVITY (Rp%): 99.9
REFLECTIVITY (Rs%): 99.99
DAMAGE THRESHOLD (PULSED): >12 J/cm² @ 1064nm, 10ns
DURABILITY: MIL-C-675A

S2: NONE

3. FINE GROUND SURFACE

4. RoHS COMPLIANT



SPECIFICATIONS SUBJECT TO CHANGE WITHOUT NOTICE
DIMENSIONS ARE FOR REFERENCE ONLY

	S1	S2
SHAPE	PLANO	PLANO
CLEAR APERTURE (%)	>90	N/A
SURFACE QUALITY	20-10	COMMERCIAL POLISH
SURFACE FLATNESS	$\lambda/8$	N/A
WAVELENGTH RANGE (nm)	515 - 532	N/A
BEVEL	PROTECTIVE AS NEEDED	PROTECTIVE AS NEEDED

<div><div>EO[®]</div><div>Edmund Optics[®]</div></div>			
TITLE		532nm, 45° 25.4mm Dia. Nd:YAG IBS Low Loss Laser Line Mirror	
DWG NO		89451	SHEET 1 OF 1

THIRD ANGLE
PROJECTION

ALL DIMS IN

mm